

Epitaxial Thin Films of $\text{ATiO}_{3-x}\text{H}_x$ (A = Ba, Sr, Ca) with Metallic Conductivity

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Supporting Information

ABSTRACT: Epitaxial thin films of titanium perovskite oxyhydride $\text{ATiO}_{3-x}\text{H}_x$ (A = Ba, Sr, Ca) were prepared by CaH_2 reduction of epitaxial ATiO_3 thin films deposited on a $(\text{LaAlO}_3)_{0.3}(\text{SrAl}_{0.5}\text{Ta}_{0.5}\text{O}_3)_{0.7}$ substrate. Secondary ion mass spectroscopy detected a substantial amount and uniform distribution of hydride within the film. $\text{SrTiO}_3/\text{LSAT}$ thin film hydridized at $530\text{ }^\circ\text{C}$ for 1 day had hydride concentration of 4.0×10^{21} atoms/ cm^3 (i.e., $\text{SrTiO}_{2.75}\text{H}_{0.25}$). The electric resistivity of all the $\text{ATiO}_{3-x}\text{H}_x$ films exhibited metallic (positive) temperature dependence, as opposed to negative as in $\text{BaTiO}_{3-x}\text{H}_x$ powder, revealing that $\text{ATiO}_{3-x}\text{H}_x$ are intrinsically metallic, with high conductivity of $10^2\text{--}10^4$ S/cm. Treatment with D_2 gas results in hydride/deuteride exchange of the films; these films should be valuable in further studies on hydride diffusion kinetics. Combined with the materials' inherent high electronic conductivity, new mixed electron/hydride ion conductors may also be possible.

Since the discovery of ferroelectricity in BaTiO_3 in 1945, perovskite titanates ATiO_3 (A = Ba, Sr, Ca) have been the subject of extensive studies and are widely used in industry as capacitors, piezoelectric transducers, and nonvolatile memories.¹ When these insulating materials are annealed in reducing atmosphere such as flowing H_2 , oxygen vacancies can be introduced,² giving rise to metallic behavior and even superconductivity in SrTiO_{3-x} .³ Recent state-of-the-art techniques to tailor atomically controlled SrTiO_3 films have led to various intriguing physical properties: thermoelectricity, quantum oscillations, and field-induced superconductivity in two-dimensional electron gases.^{4–6} Such films are also of technological importance for enhancing device performance.

We recently demonstrated that by CaH_2 reduction it is possible to incorporate a large amount of hydrogen into BaTiO_3 as an anionic solid solution, $\text{BaTiO}_{3-x}\text{H}_x$ ($x < 0.6$).⁷ $\text{SrTiO}_{3-x}\text{H}_x$ and $\text{CaTiO}_{3-x}\text{H}_x$ can also be synthesized.⁸ These oxyhydrides are stable in air (up to $200\text{ }^\circ\text{C}$) and water (up to $120\text{ }^\circ\text{C}$). Although the hydride ion (H^-) itself is a strong reductant, Ti in $\text{ATiO}_{3-x}\text{H}_x$ can stay at a moderate valence ($+4 \sim +3.4$), commonly seen in many titanium oxides (e.g., Magnéli phases $\text{Ti}_n\text{O}_{2n-1}$), and is favorable for electronic conductivity. A

pelletized sample of $\text{BaTiO}_{3-x}\text{H}_x$ exhibited semiconducting behavior with a room temperature (rt) resistivity $\sim 10^{-3}\text{--}10^{-4}$ S/cm. The situation is in marked contrast with the cobaltate oxyhydrides, $\text{LaSrCoO}_3\text{H}_{0.7}$ and $\text{Sr}_3\text{Co}_2\text{O}_{4.33}\text{H}_{0.84}$, which have unusually low Co valences of +1.7 and are insulating due to strong repulsion of the 3d electrons.^{9,10} Remarkably, the hydride ions in $\text{ATiO}_{3-x}\text{H}_x$ are exchangeable with outer gaseous hydrogen species at $\sim 400\text{ }^\circ\text{C}$,^{7,8} implying mobile character of H^- through the perovskite network.

Unlike $\text{LaSrCoO}_3\text{H}_{0.7}$,¹¹ $\text{BaTiO}_{3-x}\text{H}_x$ does not have a large number of vacancies, but still seems to have good H^- diffusion within the lattice. To unveil the mechanism of H^- mobility and further explore magnetic, electric, and optical properties, experiments using single crystals or epitaxial films are crucial. Epitaxial thin-film growth also offers a possibility for applications such as mixed hydride/electronic conducting devices and hydrogen membranes.¹² However, only powder samples are available so far,^{7,8} and the transport properties are not well understood in qualitative or quantitative terms. Sintered pellets cannot be used because high-temperature treatment ($T > 500\text{ }^\circ\text{C}$) under H_2 results in decomposition. Here, we present the fabrication of epitaxial thin films of $\text{ATiO}_{3-x}\text{H}_x$ (A = Ba, Sr, Ca) by low-temperature CaH_2 reduction of the corresponding oxide films obtained using pulsed laser deposition (PLD). These films are found to be metallic down to low temperatures, with a high conductivity of $10^2\text{--}10^4$ S/cm at rt. Hydride exchangeability with H_2 gas is also demonstrated. We expect that many future studies on H^- diffusion kinetics can be conducted by examining these films.

Precursor oxide films of insulating ATiO_3 (A = Ba, Sr, Ca) were grown epitaxially on a $(\text{LaAlO}_3)_{0.3}(\text{SrAl}_{0.5}\text{Ta}_{0.5}\text{O}_3)_{0.7}$ (LSAT) substrate by PLD with ATiO_3 targets.¹³ LSAT was employed because of the small lattice mismatch with ATiO_3 and for its inertness against CaH_2 ; i.e., the substrate remains insulating. To prepare the precursor targets, ATiO_3 powder (Rare Metallic 99.9%) was pressed into pellets and then sintered at $1200\text{ }^\circ\text{C}$ for 48 h in air. Deposition was conducted with a KrF excimer laser pulse with $\lambda = 248\text{ nm}$. The laser energy density was 0.7 J/cm^2 , and the frequency was 1 Hz. The substrate temperature during the deposition of the ATiO_3 thin

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film was set to 700 °C, while the O₂ partial pressure was kept at 5.0×10^{-2} Pa. The as-grown film was embedded with 0.2 g of CaH₂ in an evacuated Pyrex tube in a N₂-filled glovebox. The tube was sealed in a vacuum ($<2 \times 10^{-2}$ Pa), kept at 300–530 °C for 1 day, and then cooled to rt. Excess CaH₂ and CaO byproduct on the film surface were removed by washing with anhydrous acetone. After the hydride treatment, the colorless thin film changes to black regardless of the reduction temperature applied. Hydride reduction of thin-film oxides has been demonstrated previously, yielding SrFeO₂, LaNiO₂, and TiO_{2-x} from SrFeO₃, LaNiO₃, and TiO₂, respectively,^{14,15} but H⁻ incorporation into oxide thin films beyond defect concentration levels has not been accomplished yet.¹⁶

2θ - θ X-ray diffraction (XRD) measurements with Cu K α radiation were performed at rt on both as-grown and hydride-treated films. XRD patterns of as-grown SrTiO₃/LSAT film (Figure 1a) were indexed by (00l) reflections of SrTiO₃, in

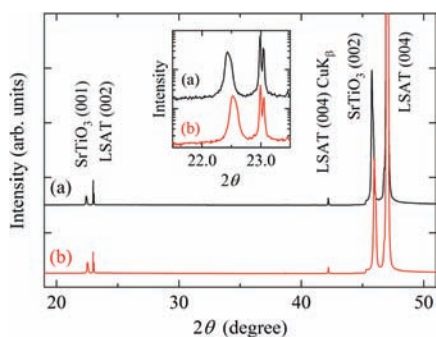


Figure 1. Out-of-plane XRD patterns of SrTiO₃/LSAT thin film: (a) as-grown and (b) after reduction/hydridization at 530 °C for 1 day. Inset: enlarged view with a logarithmic scale.

addition to those from the substrate, indicating successful growth of epitaxial SrTiO₃ film. The out-of-plane lattice parameter of as-grown film was $c = 3.964$ Å, slightly larger than that of bulk (3.905 Å) due to in-plane compression resulting from the smaller lattice parameter of the LSAT substrate (3.868 Å), and in agreement with values previously reported.^{13,17} Likewise, epitaxial thin films of BaTiO₃/LSAT ($c = 4.083$ Å) and CaTiO₃/LSAT ($c = 3.791$ Å) were fabricated. We also confirmed epitaxial growth of the films by in-plane XRD.

Figure 1b shows XRD patterns of the SrTiO₃/LSAT film treated with CaH₂ at 530 °C for 1 day. The full width at half-maximum of the 001 peak is $\sim 0.1^\circ$, almost the same as that of the as-grown film, indicating retained crystallinity during reduction. The c -axis (3.949 Å) decreases relative to the as-grown film ($\Delta c = -0.008$ Å). The degree of lattice change depends on the reduction temperature. Notably, the decrease of the c -axis in SrTiO₃ on LSAT occurred even when reduced at 300 °C (Figure S2). Changes in the c -axis were also seen in hydride-treated BaTiO₃/LSAT ($\Delta c = -0.008$ Å) and CaTiO₃/LSAT ($\Delta c = +0.018$ Å) (Figure S1).

The lattice change after hydride reduction might be due to an annealing effect where the parent oxide has not yet relaxed rather than due to the CaH₂ treatment. To check this, as-grown SrTiO₃/LSAT film was annealed at 530 °C for 1 day without CaH₂ in an evacuated Pyrex tube. In this case, Δc was less than ± 0.005 Å (Table S1), implying that the change is most likely related to compositional change (i.e., O²⁻/H⁻ exchange as mentioned later). Hydride-reduced CaTiO₃/LSAT shows

lattice expansion, as expected from results of powder samples of CaTi(O,H)₃.⁸ Hydride-treated SrTiO₃/LSAT and BaTiO₃/LSAT, in contrast, exhibit lattice contraction.^{7,8} The opposite tendency of the film (vs powder) is thus remarkable and might be explained in terms of substrate-induced strain.

It is naturally expected that hydride-treated ATiO₃/LSAT films also incorporate a large amount of H⁻ at the anionic (oxygen) site. In our previous study with powder samples, neutron diffraction and quadrupole mass spectroscopy were used to quantify the H⁻ concentration. In the present study, we use secondary ion mass spectroscopy (SIMS) to determine the amount of H⁻ within the film and its depth dependence. Figure 2 shows the dynamic SIMS depth profiles of Sr, Ti, O, H ions

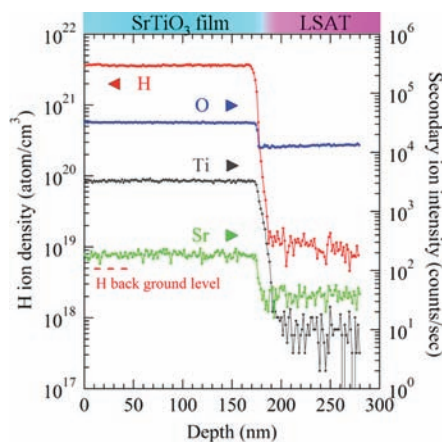


Figure 2. Dynamic SIMS depth profiles of H, Sr, Ti, O secondary ions in SrTiO₃/LSAT film, hydride-reduced at 530 °C for 1 day, showing uniform and substantial H⁻ incorporation with a composition corresponding to SrTiO_{2.75}H_{0.25}. The depth resolution is ~ 10 nm.

in SrTiO₃/LSAT film treated at 530 °C for 1 day as a typical example. The intensity of the H secondary ion signal was converted into ion density by using a standard sample prepared by ion implantation, and the depth was estimated from the sputter rate for pristine SrTiO₃.

The secondary ion intensity of Ti drastically decreased at ~ 180 nm, corresponding to the interface between SrTiO₃ film and LSAT substrate. This is also supported by a drastic decrease in Sr and O signals. Constant intensity of Sr, Ti, O along the depth direction within the SrTiO₃ film region indicates that the phase was uniform in composition and no decomposed sections were formed upon hydride reduction.

The hydrogen density in hydride-treated SrTiO₃ film is 4.0×10^{21} atoms/cm³, constant at all depths. The observed density in the film region is >2 orders of magnitude larger than in the LSAT substrate region, where the hydrogen density is background level, consistent with the fact that LSAT is not reduced by CaH₂. Previous SIMS experiments show that BaTiO₃ and SrTiO₃ films under H₂ gas atmosphere contain protons, but with much smaller quantities, $\sim 10^{20}$ atoms/cm³ ($\sim 0.5\%$ H in SrTiO₃).¹⁸ The hydrogen content in our SrTiO_{3-x}H_x film is almost 2 orders of magnitude greater than in the protonated films, close to $\sim 10^{22}$ atoms/cm³ (BaTiO_{2.4}H_{0.6}).⁷ Given the synthesis environment and incorporated hydrogen amount, the hydrogen species in the hydride-treated SrTiO₃/LSAT film are most likely H⁻, not proton or hydroxide. Hence, together with the previous results on powder,^{7,8} we conclude SrTiO_{2.75}H_{0.25} as the chemical composition.

SIMS profiles (Figure S3) for CaH₂-treated BaTiO₃ and CaTiO₃ prove also that the amount of hydrogen is several orders of magnitude greater than that of the LSAT substrate (background level, see above) and that its concentration is uniform. In SIMS measurements, chemical matrices affect sputter ion yields; thus, the overall composition must be taken into account when quantifying species. The absence of a hydrogen quantification standard for BaTiO₃ and CaTiO₃ hampered precise determination of hydrogen content. However, since all the films have the same chemical matrix except for A-site cation, we expect that the ion yields do not differ significantly. Applying the SrTiO₃ standard to the Ba and Ca samples results in hydrogen density of 1.0×10^{22} atoms/cm³ for Ba (BaTiO_{2.36}H_{0.64}) and 1.2×10^{22} atoms/cm³ for Ca (CaTiO_{2.31}H_{0.69}).

Resistivity was measured along the in-plane direction by a four-probe method. Au(30 nm)/Ti(5 nm) electrodes were deposited by electron beam deposition. Figure 3 shows

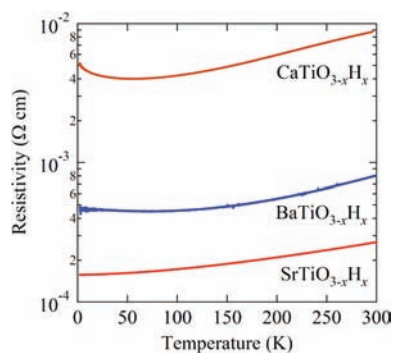


Figure 3. Typical temperature dependence of resistivity for reduced and H[−]-incorporated films: SrTiO_{2.75}H_{0.25}/LSAT, BaTi(O,H)₃/LSAT, and CaTi(O,H)₃/LSAT.

temperature dependence of the resistivity of ATiO_{3−x}H_x/LSAT films. All the films are highly conductive ($10^2 - 10^4$ S/cm). Notice again that the LSAT substrate is an insulator even after the hydride reduction. While semiconducting behavior was observed in a powder sample of BaTiO_{2.4}H_{0.6},⁷ the electrical resistivities of all of the films examined have positive temperature dependence, indicating that they are all metallic. Although we know that lattice mismatch sometimes affects transport properties,¹⁹ SrTiO_{3−x}H_x/LSAT, which has the smallest lattice mismatch (vs LSAT), exhibits metallic conductivity, implying that the metallicity is intrinsic for bulk SrTiO_{3−x}H_x. In SrTiO_{2.75}H_{0.25}/LSAT film, the observed resistivity at rt and positive temperature coefficient are comparable with those of 20% Nb-doped SrTiO₃ films ($10^3 - 10^4$ S/cm), where the doping level should be similar.²⁰ SrTiO_{3−δ} is known to be a superconductor ($T_c \approx 0.5$ K),³ but due to instrumental limits, we currently cannot verify whether our oxyhydride films are also superconducting. Bulk BaTiO_{3−x}H_x and CaTiO_{3−x}H_x are also expected to show metallic temperature dependence. The semiconducting behavior previously observed in powder samples of BaTiO_{3−x}H_x would involve a large influence from grain boundaries, as they consist of a collection of small 170 nm particles.

Generally, in oxides, the randomness induced by oxygen vacancies affects the electronic conductivity more than cation substitution. For instance, Nb doping in TiO₂ and SrTiO₃ results in 90% carrier activation;^{21,22} however, oxygen

deficiency in SrTiO₃ results in <60% carrier activation.²³ Hall measurements for SrTiO_{2.75}H_{0.25} indicate a carrier density of 4.1×10^{21} cm^{−3} at 300 K (Figure S4). This corresponds reasonably well with the H[−] amount observed with SIMS. Based on powder studies,⁷ there should be few oxygen vacancies, so the carriers should primarily be due to H[−] rather than vacancy doping. As in Nb-doped (i.e., cation-doped) SrTiO₃, carrier activation in our oxyhydride sample is also very high. While large amounts of oxygen vacancies readily induce a random potential that is detrimental to electronic conductivity, H[−] with the close ionic radius to O^{2−}, results in significantly less random potential, even at high doping levels. Another advantage of H[−] as a dopant is the ability to generate high carrier concentrations. High carrier amounts from oxygen vacancies are not possible for structural reasons. For example, oxygen vacancies >1.5 at.% result in collapse of the perovskite framework.²⁴ However, using H[−] as dopant keeps the anion sites full, removing such limits on doping.

Transport properties of H[−]-incorporated films exhibit prominent A-cation dependence, with rt resistivity descending as Ca > Ba > Sr (Figure 3). The H[−] amount and degree of lattice mismatch with LSAT substrate could account for this behavior. Furthermore, for CaTiO_{3−x}H_x/LSAT film, a change in sign of the $\rho-T$ slope was observed at ~ 50 K. Such crossover behavior has been reported in thin films of La-doped SrTiO₃ and other titanium oxides, for which various origins such as tunneling effects in the percolation model have been discussed.^{25,26} The origin of the crossover behavior in the $\rho-T$ curve of CaTiO_{3−x}H_x/LSAT should be clarified in future work.

There is a notable difference in electrical conductivity between BaTiO_{3−x}H_x and BaTiO_{3−x}. For BaTiO_{3−x}, metallic behavior was first reported by Kolodiazhnyi, perhaps with very few oxygen vacancies.²⁷ However, this metallic state is accompanied by several ferroelectric transitions (leading to symmetry changes), resulting in distinct anomalies in the $\rho-T$ curves. In contrast, BaTiO_{3−x}H_x/LSAT film exhibits a smooth temperature dependence of resistivity, indicating the absence of any structural change down to 2 K. Filling a large amount of vacancies with an anion (i.e., H[−]) seems to suppress these transitions. We also note the conductivity of BaTiO_{3−x}H_x/LSAT ($10^3 - 10^4$ S/cm) is 2–5 orders of magnitude more than that of BaTiO_{3−x}.

To investigate H[−] exchangeability, SrTiO_{2.89}H_{0.11}/LSAT film was annealed with deuterium gas at 420 °C for 6 h in an evacuated Pyrex tube. To eliminate residual O₂ and H₂O in our previous flowing D₂ setups, a small physically separated amount of CaD₂ was sealed in a tube with the SrTiO_{2.89}H_{0.11}/LSAT film. Upon heating, CaD₂ decomposed and served as a D₂ gas source. Figure 4 shows dynamic SIMS depth profile measurements of the film after D₂ treatment. An almost uniform distribution of deuteride ions along the depth direction is observed in the film region. The hydride and deuteride ion densities in the film region are 3.0×10^{20} and 1.5×10^{21} atoms/cm³, respectively. Exchange of O^{2−} for H[−]/D[−] with H₂ (D₂) gas is highly unlikely at this temperature, as demonstrated in powder sample.⁷ The H/D exchange ratio, D/(H+D), was 83%, which is almost the same as in bulk BaTiO₃ (90%). The total hydride ion density (H+D) is almost the same as the original SrTiO_{2.89}H_{0.11}/LSAT film, indicating deuteride exchange without any change in composition such as oxidation. The success of such hydride exchange in the oxyhydride film provides us an opportunity to clarify their diffusion kinetics by examining films with H/D concentration gradients.

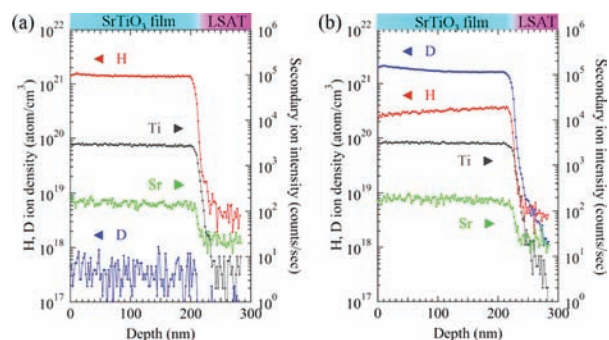


Figure 4. Dynamic SIMS depth profile of H, D, Sr, Ti secondary ions in (a) SrTiO_{2.89}H_{0.11}/LSAT and (b) SrTiO_{2.89}H_{0.02}D_{0.09}/LSAT, obtained by deuteration of SrTiO_{3-x}H_x/LSAT at 420 °C for 6 h.

In conclusion, SIMS experiments indicate a large amount of hydride (e.g., 4.0×10^{21} atoms/cm³ for A = Sr), uniform distribution in the films, and the ability of hydride to exchange with H₂ gas. Metallic conductivity (10^2 – 10^4 S/cm) was observed in a wide temperature range down to 2 K. Incorporation of hydride as a dopant allows controlling carrier levels in oxides to unprecedented amounts. This, combined with the hydride diffusion and exchange at low temperature, promises applications involving mixed electron/hydride conduction at temperatures lower than those encountered in oxide ion conduction, because the lighter mass and lower charge of hydride over oxide should make it more mobile.

With oxide ion conductors, oxide incorporation by surface reactions and their diffusion within the bulk phase and across grain boundaries have been revealed in great detail by applying a variety of experimental techniques on single crystals together with theoretical tools.^{28,29} Successful growth of oxyhydride epitaxial thin films will also enable in-depth studies on hydride diffusion kinetics and equilibrium in oxides. Additionally, intriguing properties specific to thin films have been reported, including confinement effects on SrTiO₃ and selective oxygen migration pathways for CaFeO_{2.5} with different orientations³⁰ and artificial superlattices.³¹ Similar experiments on the oxyhydride analogue would be highly interesting.

■ ASSOCIATED CONTENT

Supporting Information

XRD patterns and typical SIMS depth profiles; and Hall coefficient data. This material is available free of charge via the Internet at <http://pubs.acs.org>.

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Notes

The authors declare no competing financial interest.

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